

Biography

Munehisa Takeda was born in Japan in 1957. He received the B.E. and M.E. degrees in Precision Mechanics from Kyoto University in 1979 and 1981, respectively. He also received M.S degree in Bioengineering from UCSF/UCB in 1988 and Dr. of Information Science and Technology degree in Mechano-Informatics from The University of Tokyo in 2020. He joined Mitsubishi Electric Corporation in 1981. After having held general managers of MEMS related departments at Mitsubishi Electric Corporation, he is currently the General Manager of MEMS System Development Center at Micromachine Center. He promoted several Japanese national projects related MEMS technologies such as Micromachine project and Road infrastructure monitoring system development project. His current research interests are robotics, learning control, bioengineering, VR, micromachine, MEMS, and IoT.

Photo



Logo of the Institution

